

What is claimed is:

1. A micromirror actuator comprising:  
a substrate;  
posts formed to a predetermined height on the substrate and spaced a  
predetermined distance apart;  
a torsion bar fixed to the posts;  
a mirror coupled to the torsion bar; and  
a groove including an inclined contact surface and formed in the substrate,  
the inclined contact surface contacting the lower bottom surface of the mirror when  
the mirror is rotated.
2. The micromirror actuator of claim 1 further comprising:  
a clamping electrode for generating electrostatic forces to clamp the mirror,  
the clamping electrode formed on the inclined contact surface of the groove; and  
a magnet for generating forces to drive the mirror taking advantage of an  
external magnetic field, the magnet formed at one side of the mirror corresponding to  
the inclined contact surface.
3. The micromirror actuator of claim 1, wherein the torsion bar is formed  
on the same plane as the mirror and the mirror is formed to rotate about the torsion  
bar.
4. The micromirror actuator of claim 2, wherein the torsion bar is formed  
on the same plane as the mirror and the mirror is formed to rotate about the torsion  
bar.
5. The micromirror actuator of claim 4, wherein a plurality of magnets are  
arranged on an area of the mirror corresponding to the inclined contact surface.
6. The micromirror actuator of claim 1, wherein a plurality of magnets are  
arranged on an area of the mirror corresponding to the inclined contact surface.
7. The micromirror actuator of claim 2, wherein the mirror is formed of a  
conductive material, a driving electrode is formed at the inclined contact surface to

correspond to one side of the mirror, and an insulating layer is interposed between the driving electrode and the mirror.